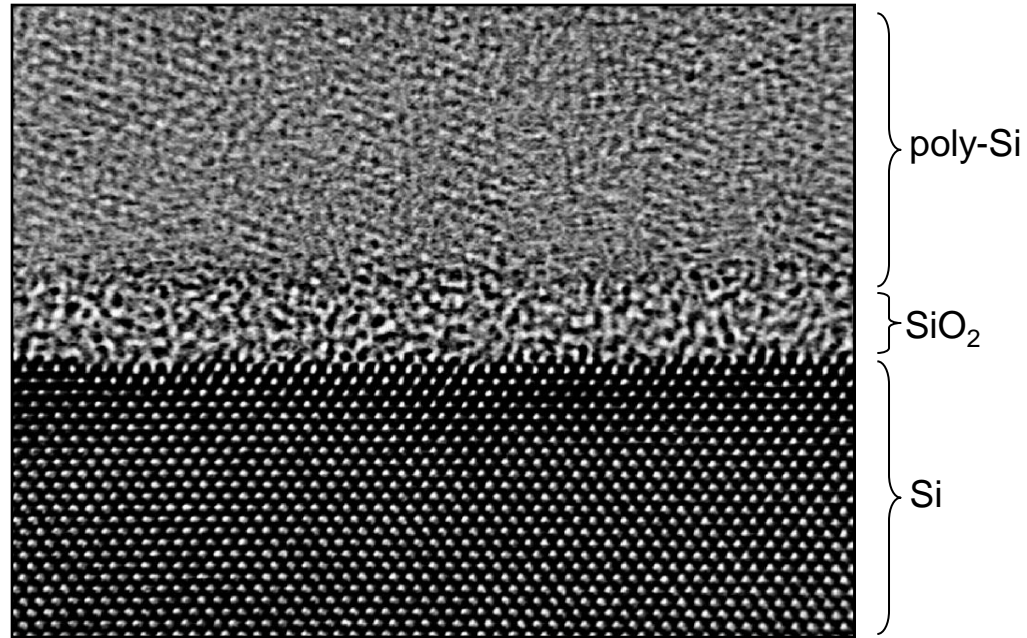
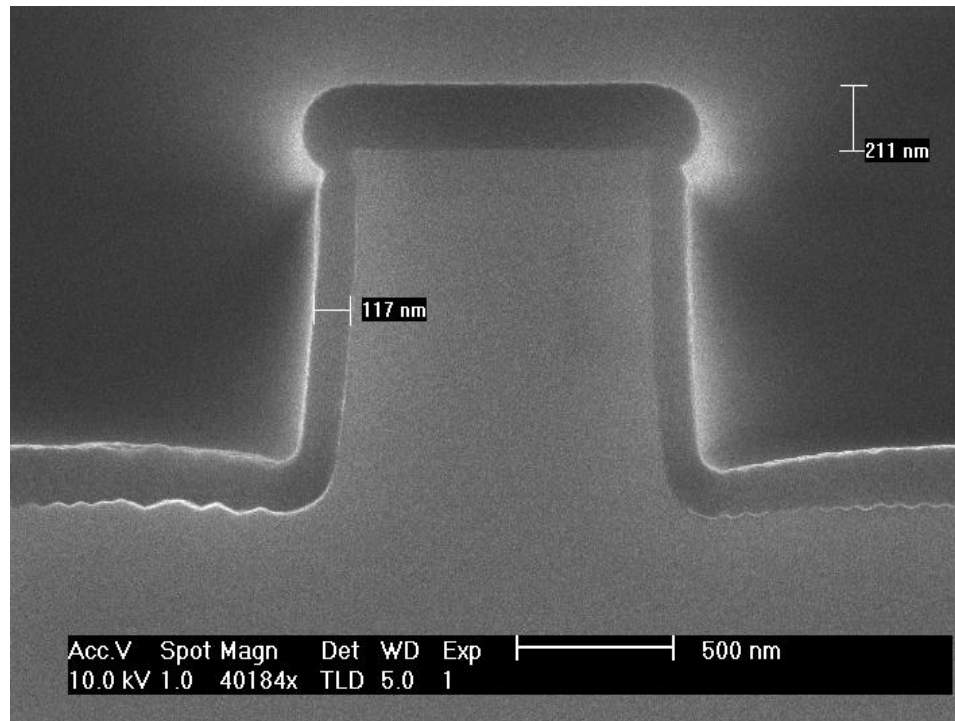


# Si – SiO<sub>2</sub> – poly-Si interface



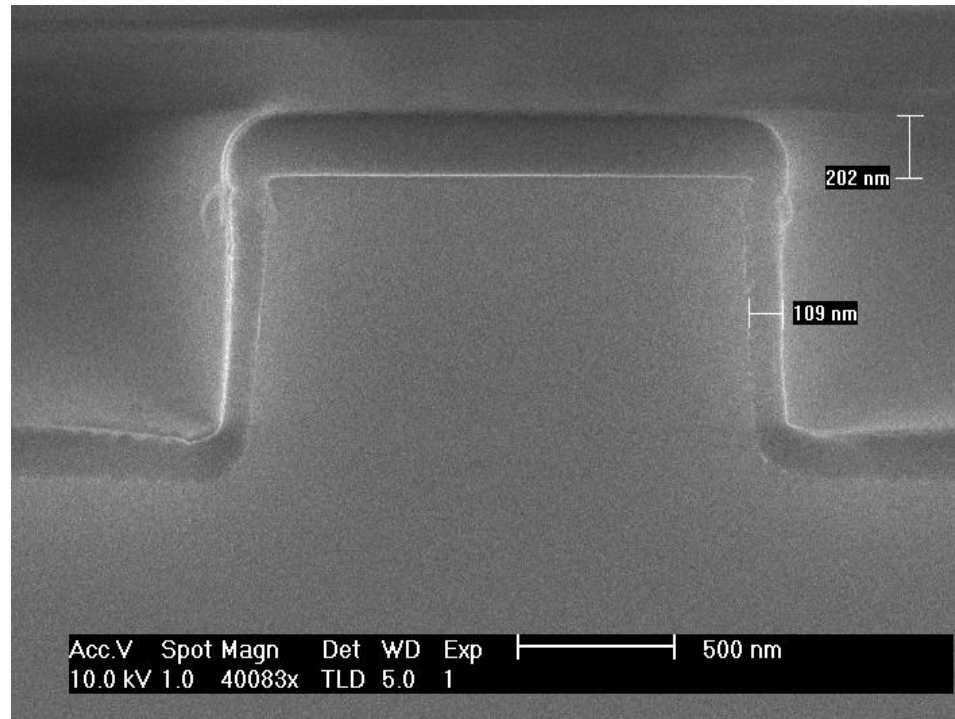
Cross-sectional transmission electron microscopy (XTEM) image of Si - SiO<sub>2</sub> - poly-Si interface, Bell Labs.

# PECVD Deposited SiO<sub>2</sub>



SEM image of PECVD SiO<sub>2</sub> on InP. PECVD deposition results in conformal coverage. Brian Thibeault, UCSB.

# ICP Deposited SiN



SEM image of ICP SiN on InP. PECVD deposition results in conformal coverage. Ilan Ben-Yaacov, UCSB.

